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APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/813,858	03/22/2001	Kent S. Wood	N.C. 79,849 3342	
26384 75	590 12/31/2002			
NAVAL RESEARCH LABORATORY ASSOCIATE COUNSEL (PATENTS) CODE 1008.2 4555 OVERLOOK AVENUE, S.W. WASHINGTON, DC 20375-5320			EXAMINER	
			LEE, SHUN K	
			ART UNIT	PAPER NUMBER
			2878	_ :
	•	•	DATE MAILED: 12/31/2002	

Please find below and/or attached an Office communication concerning this application or proceeding.

' ' ' ' ' ' ' ' ' ' ' ' ' ' ' ' ' ' '			
	Application No.	Applicant(s)	
8 0-2	09/813,858	WOOD ET AL.	* -
Office Action Summary	Examiner	Art Unit	<u> </u>
	Shun Lee	2878	
The MAILING DATE of this communication apperiod for Reply	ppears on the cover sheet w	ith the correspondence ad	dress
A SHORTENED STATUTORY PERIOD FOR REPL THE MAILING DATE OF THIS COMMUNICATION - Extensions of time may be available under the provisions of 37 CFR 1 after SIX (6) MONTHS from the mailing date of this communication. - If the period for reply specified above is less than thirty (30) days, a re - If NO period for reply is specified above, the maximum statutory period - Failure to reply within the set or extended period for reply will, by statu - Any reply received by the Office later than three months after the mailing earned patent term adjustment. See 37 CFR 1.704(b). Status		reply be timely filed ty (30) days will be considered timely ITHS from the mailing date of this co BANDONED (35 U.S.C. § 133).	mmunication.
1) Responsive to communication(s) filed on		•	•
2a)☐ This action is FINAL . 2b)⊠ T	his action is non-final.		
3) Since this application is in condition for allow closed in accordance with the practice unde Disposition of Claims			e merits is
4) Claim(s) 1-53 is/are pending in the application	on.	7	
4a) Of the above claim(s) is/are withdra	awn from consideration.		
5) Claim(s) is/are allowed.	·		·
6)⊠ Claim(s) <u>1-53</u> is/are rejected.		•	
7) Claim(s) is/are objected to.			s
8) Claim(s) are subject to restriction and/	or election requirement.		·
9) The specification is objected to by the Examin	nor	· · · · · · · · · · · · · · · · · · ·	
10) ☐ The drawing(s) filed on 22 March 2001 is/are:		ed to by the Examiner	
Applicant may not request that any objection to t	• • • • • • • • • • • • • • • • • • •		
11) The proposed drawing correction filed on		•	er.
If approved, corrected drawings are required in r			
12) ☐ The oath or declaration is objected to by the E	• •		*
Priority under 35 U.S.C. §§ 119 and 120	•		
13) Acknowledgment is made of a claim for foreign	an priority under 35 U.S.C.	§ 119(a)-(d) or (f).	
a) All b) Some * c) None of:	5		•
1. Certified copies of the priority documer	nts have been received.		
2. Certified copies of the priority documer		application No	
3. Copies of the certified copies of the pri application from the International B * See the attached detailed Office action for a lis	ority documents have been Bureau (PCT Rule 17.2(a)).	received in this National	Stage
14)⊠ Acknowledgment is made of a claim for domes	stic priority under 35 U.S.C.	§ 119(e) (to a provisional	application).
a) The translation of the foreign language p 15) Acknowledgment is made of a claim for dome	rovisional application has b	een received.	
Attachment(s)		e e e e e e e e e e e e e	-
1) Notice of References Cited (PTO-892) 2) Notice of Draftsperson's Patent Drawing Review (PTO-948) 3) Information Disclosure Statement(s) (PTO-1449) Paper No(s)	5) Notice of	Summary (PTO-413) Paper No Informal Patent Application (PTo	
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DETAILED ACTION

Information Disclosure Statement

The listing of references in the specification is not a proper information disclosure 1. statement. 37 CFR 1.98(b) requires a list of all patents, publications, or other information submitted for consideration by the Office, and MPEP § 609 A(1) states, "the list may not be incorporated into the specification but must be submitted in a separate paper." Therefore, unless the references have been cited by the examiner on form PTO-892, they have not been considered.

Drawings

The drawings are objected to as failing to comply with 37 CFR 1.84(p)(5) 2. because they include the following reference sign(s) not mentioned in the description: 600 (Fig. 11a). A proposed drawing correction, corrected drawings, or amendment to the specification to add the reference sign(s) in the description, are required in reply to the Office action to avoid abandonment of the application. The objection to the drawings will not be held in abeyance.

Specification

Applicant is reminded of the proper language and format for an abstract of the disclosure.

The abstract should be in narrative form and generally limited to a single paragraph on a separate sheet within the range of 50 to 150 words. It is important that the abstract not exceed 150 words in length since the space provided for the abstract on the computer tape used by the printer is limited. The form and legal phraseology often used in patent claims, such as "means" and "said," should be avoided. The abstract should describe the disclosure sufficiently to assist readers in deciding whether there is a need for consulting the full patent text for details.

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The language should be clear and concise and should not repeat information given in the title. It should avoid using phrases which can be implied, such as, "The disclosure concerns," "The disclosure defined by this invention," "The disclosure describes," etc.

- 4. The abstract of the disclosure is objected to because of the length and is more than a single paragraph. Correction is required. See MPEP § 608.01(b).
- 5. The disclosure is objected to because of the following informalities: on pg. 5, "11" in line 18 should probably be -11a--. Appropriate correction is required.
- 6. The lengthy specification has not been checked to the extent necessary to determine the presence of all possible minor errors. Applicant's cooperation is requested in correcting any errors of which applicant may become aware in the specification.

Claim Objections

- 7. The numbering of claims is not in accordance with 37 CFR 1.75(f) which requires that claims shall be numbered consecutively in Arabic numerals. It is noted that there are two claims numbered 25. The misnumbered claim 25 (lines 13-24 on pg. 34) have been renumbered 53.
- 8. Claim 40 is objected to under 37 CFR 1.75(c), as being of improper dependent form for failing to further limit the subject matter of a previous claim. Applicant is required to cancel the claim(s), or amend the claim(s) to place the claim(s) in proper dependent form, or rewrite the claim(s) in independent form. Claim 40 recites the limitation that said substrate <u>comprises</u> a <u>dielectric</u> whereas claim 39 recites the limitation that the substrate <u>is</u> a viscinally cut <u>dielectric</u> material. Thus claim 40 fails to further limit the subject matter of a previous claim.

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- 9. Claims 5, 6, 12, and 14 are objected to because of the following informalities:
 - (a) "heat" on line 3 of claim 4 and again on line 2 of claim 5 is indefinite and can lead to misinterpretation (if both elements are the same, the later should be identified as --said heat-);
 - (b) "heat" on line 3 of claim 4 and again on line 2 of claim 6 is indefinite and can lead to misinterpretation (if both elements are the same, the later should be identified as --said heat--);
 - (c) claim 12 recites the limitation "said dielectric substrate" in line 2 (there is insufficient antecedent basis for this limitation in the claim); and
- (d) in claim 14, "impurites" on line 1 should probably be --impurities--.

 Appropriate correction is required.

Claim Rejections - 35 USC § 112

- The following is a quotation of the second paragraph of 35 U.S.C. 112:

 The specification shall conclude with one or more claims particularly pointing out and distinctly claiming the subject matter which the applicant regards as his invention.
- 11. Claims 19-22, 43, and 49 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention.

Claims 19, 21, and 43 recite "is selected from the group comprising" renders the claims indefinite because the claims include elements not actually disclosed (those encompassed by "the group comprising"), thereby rendering the scope of the claims unascertainable.

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Claim 49 recites the limitation "said insulating layer" in line 2. There is insufficient antecedent basis for this limitation in the claim.

- 12. Claim 28 is rejected under 35 U.S.C. 112, second paragraph, as being incomplete for omitting essential structural cooperative relationships of elements, such omission amounting to a gap between the necessary structural connections. See MPEP § 2172.01. The omitted structural cooperative relationships are: a sensor to other elements (it is suggested that "a sensor," be deleted).
- 13. Claims 37-49, 50, and 51 are rejected under 35 U.S.C. 112, second paragraph, as being indefinite for failing to particularly point out and distinctly claim the subject matter which applicant regards as the invention. Applicant should note that the specification defines a lateral direction (see y axis in Fig. 11a) where a voltage differential is generated (Eq. 18) and measured.

Claim 37 recites the limitation "generating a voltage differential across the sensor in a longitudinal direction which is perpendicular to the plane of the sensor" which is vague and indefinite since it is unclear how the plane is oriented relative to the sensor.

Claims 50 and 51 recite the limitation "longitudinal direction" which is vague and indefinite since it is unclear how the longitudinal direction is oriented relative to the sensor.

Claim Rejections - 35 USC § 102

The following is a quotation of the appropriate paragraphs of 35 U.S.C. 102 that form the basis for the rejections under this section made in this Office action:

A person shall be entitled to a patent unless -

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(a) the invention was known or used by others in this country, or patented or described in a printed publication in this or a foreign country, before the invention thereof by the applicant for a patent.

15. Claims 1-19, 21, 23, 24, and 28-30 are rejected under 35 U.S.C. 102(a) as being anticipated by Van Vechten *et al.* (18th International Conference on Thermoelectrics 1999, pg. 477-480).

In regard to claim 1, Van Vechten et al. disclose (Figs. 1 and 4) a detector for detecting a photon, comprising:

- (a) a substrate,
- (b) a photon absorber (3) disposed upon said substrate,
- (c) a thermoelectric sensor (5), disposed upon said substrate and thermally coupled with said photon absorber (3), and
- (d) a heat sink (4) disposed upon said substrate, thermally coupled to the thermoelectric sensor (5),

for absorbing a photon and generating a potential across said sensor (5), whereby there is a voltage differential between said absorber (3) and said heat sink (4) in response to said photon absorption (section on "Detector design").

In regard to claim 2 which is dependent on claim 1, Van Vechten et al. also disclose (section on "Preliminary Experimental Results") means to measure said voltage differential.

In regard to claim 3 which is dependent on claim 1, Van Vechten et al. also disclose (second paragraph in "Double-Pixel Unit" section) that said substrate comprises a dielectric material.

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In regard to claim 4 which is dependent on claim 1, Van Vechten *et al.* also disclose (section on "Detector design"; Fig. 2) that responsive to arrival of a photon, said absorber is heated, and the heat in said absorber is transferred to said sensor and further transferred to said heat sink.

In regard to claim **5** which is dependent on claim 4, Van Vechten *et al.* also disclose (section on "Detector design"; Fig. 2) that said heat is transferred from said absorber to said heat sink faster than the heat is transferred from said absorber to said substrate.

In regard to claim **6** which is dependent on claim 5, Van Vechten *et al.* also disclose (section on "Detector design"; Fig. 2) that the time (~10 nsec) for said heat to be transferred from said absorber to said heat sink is about ten times less than the time (~100 nsec) for the heat to be transferred from said absorber to said substrate.

In regard to claim **7** which is dependent on claim 2, Van Vechten *et al.* also disclose (second paragraph in "Conclusions" section) that said means for measuring said voltage differential comprises superconducting leads.

In regard to claims **8** and **9** which are dependent on claim 7, Van Vechten *et al.* also disclose (section on "Preliminary Experimental Results") that said superconducting leads are electrically coupled to the input coil of a flux transformer of a superconducting quantum interference device circuit.

In regard to claim **10** which is dependent on claim 1, Van Vechten *et al.* also disclose (first paragraph in "Double-Pixel Unit" section) that the absorber and the heat sink have the same heat capacity.

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In regard to claim **11** which is dependent on claim 10, Van Vechten *et al.* also disclose (first paragraph in "Double-Pixel Unit" section) that the absorber and the heat sink are alike in material and geometry.

In regard to claim 12 which is dependent on claim 1 in so far as understood,

Van Vechten et al. also disclose (section on "Preliminary Experimental Results") that
said thermoelectric sensor comprises a thin film disposed upon said substrate.

In regard to claim 13 which is dependent on claim 1, Van Vechten et al. also disclose (section on "Preliminary Experimental Results") that said thermoelectric sensor comprises a material with isotropic thermoelectric properties.

In regard to claim **14** which is dependent on claim 12, Van Vechten *et al.* also disclose (section on "Preliminary Experimental Results") that said thin film comprises gold with impurities.

In regard to claim **15** which is dependent on claim 12, Van Vechten *et al.* also disclose (section on "Preliminary Experimental Results") that said thin film comprises gold with iron impurities between about 10 ppm and 100 ppm.

In regard to claim **16** which is dependent on claim 12, Van Vechten *et al.* also disclose (third paragraph in "Introduction" section) that said thin film comprises a metal (e.g., Au,Fe or Au, Mn) with a Seebeck coefficient of at least about 10 µV/K at an operating temperature of said detector.

In regard to claim 17 which is dependent on claim 12, Van Vechten et al. also disclose (third paragraph in "Introduction" section) that said thin film comprises a metal

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(e.g., Au,Fe or Au, Mn) with a Seebeck coefficient of between about 10 μ V/K and about 80 μ V/K at an operating temperature of said detector.

In regard to claim 18 which is dependent on claim 12, Van Vechten et al. also disclose (third paragraph in "Introduction" section and section on "Preliminary Experimental Results") that said thin film comprises lanthanum cerium hexaboride.

In regard to claim **19** which is dependent on claim 1 in so far as understood, Van Vechten *et al.* also disclose (Fig. 4) that said photon absorber comprises of a material selected from the group of Be, As, Sb, Bi, Au, Ag, and W.

In regard to claim 21 which is dependent on claim 1 in so far as understood, Van Vechten et al. also disclose (Fig. 4) that said heat sink comprises of a material selected from the group of Be, As, Sb, Bi, Au, Ag, and W.

In regard to claim **23** which is dependent on claim 1, Van Vechten *et al.* also disclose (second paragraph in "Double-Pixel Unit" section) a superconducting element (*i.e.*, superconducting strip in Fig. 1) electrically coupled to the heat sink and the photon absorber.

In regard to claim **24** which is dependent on claim 1, Van Vechten *et al.* also disclose (Figs. 1 and 4) that said sensor (5) is between said absorber (3) and said heat sink (4).

In regard to claim **28** in so far as understood, the method steps are implicit for the apparatus of Van Vechten *et al.* since the structure is the same as the applicant's apparatus of claim 3.

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In regard to claim **29** which is dependent on claim 1, Van Vechten *et al.* also disclose (Eq. 9) that said sensor has a resistance R which is less than r_0L_0/T^2A_{abs} , where r_0 is the Kapitza resistance constant between the absorber and the substrate, L_0 is the Lorenz number, T is the operating temperature of the detector, and A_{abs} , is the cross sectional area of the absorber.

In regard to claim **30** which is dependent on claim 29, Van Vechten *et al.* also disclose that said r₀ is about 20 K⁴cm²/W (first paragraph in "Signal to Noise ratio" section) and said L₀ is about 25 nW-Ω/K² (second paragraph in "Introduction" section).

16. Claims 37-43, 46-48, 50, and 51 are rejected under 35 U.S.C. 102(a) as being anticipated by Gulian *et al.* (IEEE Trans. on Applied Superconductivity 1999, 9:3194-3197) in so far as understood.

In regard to claim **37**, Gulian *et al.* disclose (Fig. 4) a photon detector comprising:

(a) a substrate, and

(b) a thermoelectric sensor comprising a thin anisotropic superconducting film (section II), disposed upon the substrate,

for receiving photons and for generating a voltage differential across the sensor in a longitudinal direction which is perpendicular to the plane of the sensor.

In regard to claim **38** which is dependent on claim **37**, Gulian *et al.* also disclose (section II) that the Seebeck coefficient of the sensor in one direction is larger than in other directions.

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In regard to claims **39** and **40** which are dependent on claim 38, Gulian *et al.* also disclose (section III) that the substrate is a viscinally cut dielectric material having a tilt angle less than about 45 degrees between the sensor's a-b plane and longitudinal axis.

In regard to claim **41** which is dependent on claim 37, Gulian *et al.* also disclose (section II) that said thin anisotropic superconducting film has an effective length L in the longitudinal direction much greater than its thickness.

In regard to claim **42** which is dependent on claim 37, Gulian *et al.* also disclose (section II) that said thin anisotropic superconducting film comprises a oxide-layered superconducting film in normal state.

In regard to claim **43** and **46** which are dependent on claim 42, Gulian *et al.* also disclose (section II and References 4-11) that said oxide-layered superconducting film comprises of a material selected from the group of YBaCuO (*i.e.*, YBa₂Cu₃O₇), LaCuO, and LaBaCuO.

In regard to claim **47** which is dependent on claim 37, Gulian *et al.* also disclose (first four paragraphs in section IV) an insulating layer disposed upon said sensor and a normal-metal absorber disposed upon said insulating layer, said absorber for absorbing incident photons, and said insulating layer for preventing electrical shorts between portions of said sensor.

In regard to claim **48** which is dependent on claim 47, Gulian *et al.* also disclose (sixth paragraph in section IV) that said normal-metal absorber is tungsten.

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In regard to claim **50**, Gulian *et al.* is applied as in claims 39 and 42 above. Gulian *et al.* also disclose (section III) a viscinally cut dielectric substrate having a tilt angle of about 5 degrees.

In regard to claim **51**, Gulian *et al.* is applied as in claims 39 and 47 above. Gulian *et al.* also disclose (third paragraph in section III) a viscinally cut dielectric substrate having a tilt angle of less than about 5 degrees.

Claim Rejections - 35 USC § 103

- 17. The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:
 - (a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.
- 18. This application currently names joint inventors. In considering patentability of the claims under 35 U.S.C. 103(a), the examiner presumes that the subject matter of the various claims was commonly owned at the time any inventions covered therein were made absent any evidence to the contrary. Applicant is advised of the obligation under 37 CFR 1.56 to point out the inventor and invention dates of each claim that was not commonly owned at the time a later invention was made in order for the examiner to consider the applicability of 35 U.S.C. 103(c) and potential 35 U.S.C. 102(e), (f) or (g) prior art under 35 U.S.C. 103(a).
- 19. Claims 20, 22, 25, 26, and 53 are rejected under 35 U.S.C. 103(a) as being unpatentable over Van Vechten *et al.* (18th International Conference on Thermoelectrics 1999, pg. 477-480) in view of Blomberg *et al.* (US 6,177,673).

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In regard to claim **20** which is dependent on claim 19 in so far as understood, the detector of Van Vechten *et al.* lacks that said photon absorber comprises bismuth. Photon absorbers are well known in the art. For example, Blomberg *et al.* teach (column 1, lines 35-38) it is well known in the art that broadband photon absorbers comprise of bismuth. Therefore it would be obvious to one of ordinary skill to provide a photon absorber comprising bismuth in the detector of Van Vechten *et al.*, in order to obtain a broadband photon absorber.

In regard to claim 22 which is dependent on claim 21 in so far as understood, the detector of Van Vechten et al. lacks that said heat sink comprises bismuth. Photon absorbers are well known in the art. For example, Blomberg et al. teach (column 1, lines 35-38) it is well known in the art that broadband photon absorbers comprise of bismuth. Van Vechten et al. also disclose (first paragraph in "Double-Pixel Unit" section) that the absorber and the heat sink are alike in material and geometry and have the same heat capacity. Therefore it would be obvious to one of ordinary skill to provide a photon absorber comprising bismuth and a heat sink comprising bismuth in the detector of Van Vechten et al., in order to obtain a broadband photon absorber and a heat sink that are alike in material and geometry and have the same heat capacity.

In regard to claim 25, Van Vechten et al. is applied as in claim 15 above and Van Vechten et al. in view of Blomberg et al. is applied as in claim 22 above.

Van Vechten et al. also disclose (second paragraph in "Double-Pixel Unit" section) that said substrate comprises a dielectric material. The modified detector of Van Vechten et al. lacks an explicit description that the dielectric material is a silicon.

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Silicon substrates are well known in the art. Therefore it would be obvious to one of ordinary skill to provide a known silicon substrate as the substrate in the modified detector of Van Vechten et al.

In regard to claim **26**, Van Vechten *et al.* in view of Blomberg *et al.* is applied as in claim 25 above. Van Vechten *et al.* also disclose (fourth paragraph in "Introduction" section) a photon metallic absorber comprising the metal Sb. The modified detector of Van Vechten *et al.* lacks that the absorber and heat sink have a width of 18 µm, a length of 22 µm, a thickness of 0.2 µm, and that the sensor have dimensions of 2 µm in width, 26 µm in length, and 0.5 µm in thickness. However, Van Vechten *et al.* also disclose ("Electron-Phonon Decoupling", "Signal to Noise Ration", and "Double Pixel Unit" sections) how to size the sensor, absorber, and heat sink to achieve a desired signal duration and signal to noise ratio. Therefore it would be obvious to one of ordinary skill to size the sensor, absorber, and heat sink in the modified detector of Van Vechten *et al.* in order to achieve a desired signal duration and signal to noise ratio.

In regard to claim **53**, Van Vechten *et al.* is applied as in claim 18 above and Van Vechten *et al.* in view of Blomberg *et al.* is applied as in claim 22 above. The modified detector of Van Vechten *et al.* lacks an explicit description that the dielectric material is a silicon. Silicon substrates are well known in the art. Therefore it would be obvious to one of ordinary skill to provide a known silicon substrate as the substrate in the modified detector of Van Vechten *et al.*

20. Claim 27 is rejected under 35 U.S.C. 103(a) as being unpatentable over

Van Vechten et al. (18th International Conference on Thermoelectrics 1999, pg. 477-

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480) in view of Blomberg *et al.* (US 6,177,673) as applied to claim 26 above, and further in view of Kampwirth *et al.* (US 4,266,008) and Rosheim (US 4,691,973).

In regard to claim 27 which is dependent on claim 26, Van Vechten et al. also disclose (second paragraph in "Conclusions" section) that superconducting electric leads attached to said heat sink and to said absorber for measuring said voltage differential (see voltage in Fig. 1). The modified detector of Van Vechten et al. lacks the superconducting electric leads are niobium. Superconducting electric leads such as niobium are well known in the art. For example, Kampwirth et al. teach (column 2, lines 42-45) that superconducting electric leads comprise niobium. As another example, Rosheim teaches (column 1, lines 6-31) that superconducting electric leads comprise niobium. Therefore it would be obvious to one of ordinary skill that the superconducting electric leads in the modified detector of Van Vechten et al. are well known superconducting electric leads such as niobium superconducting electric leads.

21. Claims 31-36 are rejected under 35 U.S.C. 103(a) as being unpatentable over Van Vechten *et al.* (18th International Conference on Thermoelectrics 1999, pg. 477-480) in view of Lehovec (US 3,748,479).

In regard to claims 31-33 and 36, Van Vechten et al. is applied as in claim 1 above. The photon detector (or photon detector array) of Van Vechten et al. lacks that the photon absorber, the heat sink, and the thermoelectric sensor are disposed on the edge of the wafer and a voltage differential measuring means disposed upon a face of the wafer. Multichip integrated circuit packages for detectors are well known in the art. For example, Lehovec teaches (column 1, line 10 to column 2, line 13) to dispose

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photodetectors on the edge of a slab (*i.e.*, wafer) and to dispose associated electrical circuitry upon a face of the slab (*i.e.*, wafer) in order to provide each photodetector with its own individual electrical circuitry. Therefore it would be obvious to one of ordinary skill to dispose the photon absorber, the heat sink, and the thermoelectric sensor on the edge of the substrate and to dispose the voltage differential measuring means upon a face of the substrate in the detector of Van Vechten *et al.*, in order to provide each photon detector with its own individual voltage differential measuring means.

In regard to claims **34** and **35** which are dependent on claim 33, Van Vechten *et al.* also disclose (section on "Preliminary Experimental Results") that said voltage differential measuring means comprises a SQUID array amplifier (*i.e.*, semiconductor electronics).

Claims 44 and 45 are rejected under 35 U.S.C. 103(a) as being unpatentable over Gulian *et al.* (IEEE Trans. on Applied Superconductivity 1999, 9:3194-3197) in view of Himpsel (US 5,296,458) in so far as understood.

In regard to claims **44** and **45** which are dependent on claim 42, the detector of Gulian *et al.* lacks an explicit description that said oxide-layered superconducting film comprises La₂CuO_{4+δ} or La_{2-x}Ba_xCuO₄. However, copper oxide layered superconductors such as La₂CuO_{4+δ} or La_{2-x}Ba_xCuO₄ are well known in the art. For example, Himpsel teach (column 1, lines 17-46; column 3, lines 56-64) it is well known in the art that oxide-layered superconductors comprise La₂CuO_{4+δ} or La_{2-x}Ba_xCuO₄. Therefore it would be obvious to one of ordinary skill to provide a well known copper oxide layered superconductor (*e.g.*, La₂CuO_{4+δ} or La_{2-x}Ba_xCuO₄) as the oxide-layered

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superconductor in the detector of Gulian et al., in order to fabricate an anisotropic sensor.

23. Claim 49 is rejected under 35 U.S.C. 103(a) as being unpatentable over Gulian et al. (IEEE Trans. on Applied Superconductivity 1999, 9:3194-3197) in so far as understood.

In regard to claim **49** which is dependent on claim 37, the detector of Gulian *et al.* lacks a non-electrically conducting absorber disposed upon said sensor, said absorber for absorbing photons. Gulian *et al.* also disclose (fourth paragraph in section IV) an insulated absorber (*i.e.*, a non-electrically conducting absorber) so as to prevent shorting out the sensor. Therefore it would be obvious to one of ordinary skill to provide a non-electrically conducting absorber in the detector of Gulian *et al.*, in order to prevent shorting out the sensor.

Claim 52 is rejected under 35 U.S.C. 103(a) as being unpatentable over
 Van Vechten *et al.* (18th International Conference on Thermoelectrics 1999, pg. 477-480) in view of Applicant's Admitted Prior Art.

In regard to claim **52** which is dependent on claim 12, the modified detector of Van Vechten *et al.* lacks that said thin film comprises CeNiSn. Materials having a large seebeck coefficient such as CeNiSn are well known in the art. For example, applicant admits as Prior Art (pg. 16, lines 3-8) it is known in the art that CeNiSn have a large seebeck coefficient (e.g., ~60 µV/K). Therefore it would be obvious to one of ordinary skill to provide a high seebeck coefficient (e.g., CeNiSn) material for the thin film in the

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detector of Van Vechten et al. in order to achieve a desired signal duration and signal to noise ratio.

Conclusion

25. Any inquiry concerning this communication or earlier communications from the examiner should be directed to Shun Lee whose telephone number is (703) 308-4860. The examiner can normally be reached on Tuesday-Thursday.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, David Porta can be reached on (703) 308-4852. The fax phone numbers for the organization where this application or proceeding is assigned are (703) 872-9318 for regular communications and (703) 872-9319 for After Final communications.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

December 26, 2002

DAMP CHANG

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